IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Leonard Forbes et al.

Title:

PROGRAMMABLE MEMORY CELL USING CHARGE TRAPPING IN A GATE OXIDE

Docket No.:

303.588US3

Filed:

January 22, 2004

Examiner:

Tuan Nguyen

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

APR 1 9 2004 C

Serial No.: 10/763,136

Due Date: N/A

Group Art Unit: Unknown

We are transmitting herewith the following attached items (as indicated with an "X"):

- X A return postcard.
- X A Communication Concerning Related Applications (2 pgs.).
- X A Supplemental Information Disclosure Statement (2 pgs.), Form 1449 (4 pgs.), and copies of 35 cited documents.

If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

Customer Number 21186

Atty: Daniel J. Kluth Reg. No. 32,146

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 15 day of April, 2004.

MEREDITH MESCHER

Name

Signature

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

(GENERAL)

- AIN 13

<u>S/N 10/763136</u> PATENT

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COMMUNICATION CONCERNING RELATED APPLICATION(S)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Applicants would like to bring to the Examiner's attention the following related application(s) in the above-identified patent application:

Serial/Patent No. 08/969,099	Filing Date November	Attorney Docket 303.362US1	Title MEMORY USING INSULATOR TRAPS
6,232,643 09/388,656 6,246,606	13, 1997 September 2, 1999	303.362US2	MEMORY USING INSULATOR TRAPS
09/394,109 6,140,181	September 10, 1999	303.362US3	MEMORY USING INSULATOR TRAPS
09/858,304 6,545,314	May 15, 2001	303.362US4	MEMORY USING INSULATOR TRAPS
09/879,453 6,351,411	June 12, 2001	303.362US5	MEMORY USING INSULATOR TRAPS
09/383,804 6,521,958	August 26, 1999	303.588US1	MOSFET TECHNOLOGY FOR PROGRAMMABLE ADDRESS DECODE AND CORRECTION
09/924,659 6,700,821	August 8, 2001	303.588US2	MOSFET TECHNOLOGY FOR PROGRAMMABLE ADDRESS DECODE AND CORRECTION
09/782,543 6,674,667	February 13, 2001	303.620US1	PROGRAMMABLE FUSE AND ANTIFUSE AND METHOD THEREFOR
10/719,217	November 20, 2003	303.620US2	PROGRAMMABLE FUSE AND ANTIFUSE AND METHOD THEREFOR

COMMUNICATION CONCERNING RELATED APPLICATIONS

Serial Number: 10/763136

Filing Date: January 22, 2004

Title: PROGRAMMABLE MEMORY CELL USING CHARGE TRAPPING IN A GATE OXIDE

Page 2 Dkt: 303.588US3

Respectfully submitted,

LEONARD FORBES ET AL.

By Applicants' Representatives,

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A. P.O. Box 2938
Minneapolis, MN 55402

(612) 373-6904

Date <u>Apr 15, 2004</u>

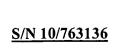
Daniel J. Kluth

Reg. No. 32,146

<u>CERTIFICATE UNDER 37 CFR 1.8:</u> The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this <u>15</u> day of <u>April</u>, 2004.

MEREDINH MESCHER

Signature



ATES PATENT AND TRADEMARK OFFICE

Applicant: Leonard Forbes et al. Examiner:

Tuan Nguyen

Serial No.:

10/763,136

Group Art Unit:

Unknown

Filed:

January 22, 2004

Docket:

Title:

303.588US3

PROGRAMMABLE MEMORY CELL USING CHARGE TRAPPING IN A

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with 37 C.F.R. §§ 1.97 et. seq., the enclosed materials are brought to the attention of the Examiner for consideration in connection with the above-identified patent application. Applicants respectfully request that this Supplemental Information Disclosure Statement be entered and the documents listed on the attached Form 1449 be considered by the Examiner and made of record. Pursuant to the provisions of MPEP 609, Applicants request that a copy of the 1449 form, initialed as being considered by the Examiner, be returned to the Applicants with the next official communication.

Pursuant to 37 C.F.R. §1.97(b), it is believed that no fee or statement is required with the Supplemental Information Disclosure Statement. However, if an Office Action on the merits has been mailed, the Commissioner is hereby authorized to charge the required fees to Deposit Account No. 19-0743 in order to have this Supplemental Information Disclosure Statement considered.

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Serial No :10/763136

Filing Date: January 22, 2004

Title: PROGRAMMABLE MEMORY CELL USING CHARGE TRAPPING IN A GATE OXIDE

Page 2 Dkt: 303.588US3

The Examiner is invited to contact the Applicants' Representative at the below-listed telephone number if there are any questions regarding this communication.

The present application is either a U.S. national patent application filed after June 30, 2003 or an international application that entered the national stage under 35 U.S.C. § 371 after June 30, 2003. Thus, Applicant believes that the U.S. Patent & Trademark Office has waived the requirement under 37 C.F.R. 1.98 (a)(2)(i) for submitting a copy of each cited U.S. patent and each U.S. patent application publication. The waiver is provided in a pre-OG notice from the U.S. Patent & Trademark Office entitled "Information Disclosure Statements May Be Filed Without Copies of U.S. Patents and Published Applications in Patent Applications filed after June 30, 2003" and dated July 11, 2003. Applicant acknowledges the requirement to submit copies of foreign patent documents and non-patent literature in accordance with 37 C.F.R. 1.98(a)(2).

Respectfully submitted,

LEONARD FORBES ET AL.

By their Representatives,

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A. P.O. Box 2938
Minneapolis, MN 55402
(612) 373-6904

Kluth

Date Apr. 15, 2004

Daniel J. Kluth

Reg. No. 32,146

MEREDITH MESCHER

Meredeth Mescher

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INFORMATION DISCLOSURE
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When the substitute of the s Complete if Known 10/763136 **Application Number Filing Date** January 22, 2004 Forbes, Leonard **First Named Inventor Group Art Unit** Unknown Nguyen, Tuan **Examiner Name** Attorney Docket No: 303.588US3 Sheet 1 of 4

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Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	T ²

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Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
		"MT28F002B5 Flash Memory Data Sheet", Micron Technology, Inc., (Jan	

EXAMINER

DATE CONSIDERED

PTO/SB/08A(10-01)
Approved for use through 10/31/2002, OMB 651-0031
US Patent & Trademark Office: U.S. DEPARTMENT OF COMMERCE and to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/PTO INFORMATION DISCLOSURE	Complete if Known			
STATEMENT BY APPLICANT	Application Number	10/763136		
(Use as many sheets as necessary)	Filing Date	January 22, 2004		
	First Named Inventor	Forbes, Leonard		
	Group Art Unit	Unknown		
	Examiner Name Nguyen, Tuan			
Sheet 2 of 4	Attorney Docket No: 3	303.588US3		

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Application Number	10/763136		
(Use as many sheets as necessary)	Filing Date	January 22, 2004		
	First Named Inventor	Forbes, Leonard		
	Group Art Unit	Unknown		
	Examiner Name	Nguyen, Tuan		
Sheet 3 of 4	Attorney Docket No: 3	303.588US3		

Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s),	T
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Substitute for form 1449A/PTO Complete if Known INFORMATION DISCLOSURE **Application Number** 10/763136 STATEMENT BY APPLICANT (Use as many sheets as necessary) January 22, 2004 Filing Date **First Named Inventor** Forbes, Leonard **Group Art Unit** Unknown Nguyen, Tuan **Examiner Name** Attorney Docket No: 303.588US3 Sheet 4 of 4

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Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
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